



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/360,292  
Filing Date ..... July 22, 1999  
Inventor..... Sujit Sharan et al.  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 1765  
Examiner ..... Ahmed, Shamim  
Attorney's Docket No. .... MI22-1106  
Title: Plasma Etching Process

**RESPONSE TO AUGUST 18, 2004 FINAL OFFICE ACTION**  
**TO ACCOMPANY RCE FILING**

To: Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 W. First Avenue, Suite 1300  
Spokane, WA 99201-3828

**AMENDMENTS**

**Introductory Comments**

In response to the Office Action dated August 18, 2004, applicant amends and remarks as follows.